ABSTRACT

There is disclosed a piezoelectric thin film having less non-uniform portion and holding satisfactory piezoelectric characteristics, a method 5 of manufacturing the film, a piezoelectric element using the piezoelectric thin film, and an ink jet system recording head using the piezoelectric element. In the piezoelectric thin film of perovskite crystals 10 formed on a substrate by a sol-gel process and represented by a general formula $Pb_{(1-x)}La_x(Zr_yTi_{1-y})O_3$ (where $0 \le x < 1$, $0.05 \le y \le 1$), a film thickness of the thin film is 1000 nm or more and 4000 nm or less, and a difference between a maximum value and a 15 minimum value of y in an arbitrary portion of the thin film is 0.05 or less.